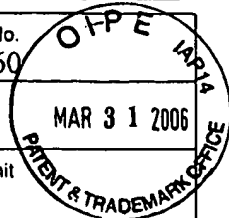


Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 09712-332001	Application No. 10/659,060
Information Disclosure Statement by Applicant (Use several sheets if necessary)		Applicant Peter J. de Groot	
		Filing Date September 9, 2003	Group Art Unit 2877

(37 CFR §1.98(b))



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Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
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	AP	2004/0189999	09/30/2004	de Groot et al.			
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	AV	2005/0088663	4/28/2005	de Groot et al.			
	AW	2005/0146727	7/7/2005	Hill			
V	AX	2005/0237534	10/27/2005	Deck			
MD	AY	2006/0012582	01/19/2006	de Lega			
MD	AZ	H1972 H	07/03/2001	Inoue			
	AAA						

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							Yes	No
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	BC	DE 4108944	09/24/1992	Germany	G01B	9/02	Abstract Only	
	BD	DE 4309056	09/22/1994	Germany	G01B	9/02	Abstract Only	
	BE	GB 2385417	08/20/2003	Great Britain	G01B	11/24		
	BF	WO 97/44633	11/27/1997	WIPO	G01B	11/24		
	BG	WO 02/082008	10/17/2002	WIPO	G01B	9/02		
MD	BH	WO 03/062802	07/31/2003	WIPO	G01N	21/47		
	BI							
	BJ							

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MD	BK	C. Akcay et al., "Spectral shaping to improve the point spread function in optical coherence tomography", <u>Optics Letters</u> , Vol. 28, No. 20, pp. 1921-1923 (October 15, 2003)
	BL	R.M.A. Azzam et al., "Reflection and Transmission of Polarized Light by Stratified Planar Structures", <u>Ellipsometry and Polarized Light</u> , Elsevier Science B.V. ISBN 0 444 87016 4 (Paperback) pp. 267-363 (1987)
	BM	R.M.A. Azzam et al., "Ellipsometric function of a film-substrate system: Applications to the design of reflection-type optical devices and to ellipsometry", <u>Journal of the Optical Society of America</u> , Vol. 5, No. 3, pp. 252-260
	BN	M. Bashkansky et al., "Signal Processing for Improving Field Cross-correlation Function in Optical Coherence Tomography", <u>Supplement to Optics & Photonics News</u> , 9(5) (May, 1998)
	BO	Berman et al., "Review of In Situ & In-line Detection for CMP Applications", <u>Semiconductor Fabtech - 8th Edition</u> , pp. 267-274
	BP	A. Bosseboeuf et al., "Application of microscopic interferometry techniques in the MEMS field", <u>Proc. SPIE</u> , 5145, pp. 1-16 (2003)
	BQ	M. Davidson et al., "An Application of Interference Microscopy to Integrated Circuit Inspection and Metrology", <u>Proceedings of SPIE</u> , Vol. 775, pp. 233-247 (1987)
	BR	J.E. Greivenkamp, "Generalized data reduction for heterodyne interferometry", <u>Opt. Eng.</u> , Vol. 23 No.4, pp. 350-352 (July/August 1984)
	BS	P de Groot et al., "Signal modeling for low coherence height-scanning interference microscopy", <u>Applied Optics</u> , Vol. 43 No. 25, pp. 4821-4830 (September 1, 2004)
MD	BT	P. de Groot, "Derivation of algorithms for phase-shifting interferometry using the concept of a data-sampling window", <u>Appl. Opt.</u> , 34(22), p. 4723-4730 (1995)

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↓	CC	P.A. Flournoy et al., "White-light interferometric thickness gauge", <u>Appl. Opt.</u> , 11(9), pp. 1907-1915 (1972)
↓	CD	G. Hausler et al., "Coherence Radar and Spectral Radar - New Tools for Dermatological Diagnosis", <u>Journal of Biomedical Optics</u> , Vol. 3, No. 1, pp. 21-31 (January, 1998)
MD	CE	R.D. Holmes et al., "Scanning microellipsometry for extraction of true topography", <u>Electronics Letters</u> , Vol. 31, No. 5, pp. 358-359 (March 2, 1995)
—	CF	Seung-Woo Kim et al., "Thickness-profile measurement of transparent thin-film layers by white-light scanning interferometry", <u>Applied Optics</u> , Vol. 38, No. 28, pp. 5968-5973 (October 1, 1999)
MD	CG	Kieran G. Larkin, "Efficient nonlinear algorithm for envelope detection in white light interferometry", <u>J. Opt. Soc. Am A</u> , pp. 832-843 (1996)
↓	CH	Kujawinska, Malgorzata, "Spatial Phase Measurement Methods", <u>Interferogram Analysis: Digital Fringe Pattern Measurement Techniques</u> , IOP Publishing Ltd. 1993, pp. 141-193
↓	CI	Lee et al., "Profilometry with a coherence scanning microscope", <u>Appl. Opt.</u> , 29(26), pp. 3784-3788 (1990)
↓	CJ	I. Lee-Bennett, "Advances in non-contacting surface metrology", <u>OF&T Workshop</u> , paper OTuC1 (2004)
↓	CK	K. Leonhardt et al., "Micro-Ellipso-Height-Profilometry", <u>Optics Communications</u> , Vol. 80, No. 3, 4, pp. 205-209 (January 1, 1991)
↓	CL	Y. Liu et al., "Common path interferometric microellipsometry", <u>SPIE</u> , Vol. 2782, pp. 635-645 (1996)
↓	CM	Lyakin et al., "The interferometric system with resolution better than coherence length for determination of geometrical thickness and refractive index of a layer object", <u>Proceedings of the SPIE - The International Society for Optical Engineering SPIE-INT. Soc. Opt. Eng USA</u> , Vol. 4956, pp. 163-169 (July, 2003)
↓	CN	C.J. Morgan, "Least-Squares estimation in phase-measurement interferometry", <u>Apt. Let.</u> , 7(8), pp. 368-370 (1982)
↓	CO	Ngoi et al., "Phase-shifting interferometry immune to vibration", <u>Applied Optics</u> , Vol. 40, No. 19, pp. 3211-3214 (2001)
↓	CP	A.V. Oppenheim et al., "10.3: The time-dependent Fourier Transform", <u>Discrete-Time Signal Processing</u> , 2 nd Edition, pp. 714-722 (Prentice Hall, New Jersey, 1999)
↓	CQ	M.C. Park et al., "Direct quadratic polynomial fitting for fringe peak detection of white light scanning interferograms", <u>Opt. Eng.</u> , 39(4), pp. 952-959 (2000)
↓	CR	W.H. Press et al., "Linear Correlation", <u>Numerical Recipes in C</u> , Cambridge University Press, 2 nd Edition, pp. 636-639 (1992)
↓	CS	P. Sandoz et al., "Optical implementation of frequency domain analysis for white light interferometry", <u>Proceedings SPIE</u> , Vol. 2545, pp. 221-228 (June, 1995)
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↓	DB	U. Schnell et al., "Dispersive white-light interferometry for absolute distance measurement with dielectric multilayer systems on the target", <u>Optics Letters</u> , Vol. 21, No. 7, pp. 528-530 (April, 1996)
	DC	J. Schwider et al., "Dispersive interferometric profilometer", <u>Optics Letters</u> , Vol. 19, No. 13, pp. 995-997 (July, 1994)
	DD	C.W. See et al., "Scanning optical microellipsometer for pure surface profiling", <u>Applied Optics</u> , Vol. 35, No. 34, pp. 6663-6668 (December 1, 1996)
	DE	M. Totzeck, "Numerical simulation of high-NA quantitative polarization microscopy and corresponding near-fields", <u>Optik</u> , Vol. 112, No. 9, pp. 399-406 (2001)
	DF	R. Tripathi et al., "Spectral shaping for non-Gaussian source spectra in optical coherence tomography", <u>Optics Letters</u> , Vol. 27, No. 6, pp. 406-408 (2002)
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	DH	
	DI	

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Applicant
Peter J. de GrootFiling Date
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2877**U.S. Patent Documents**

Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
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MD	AB	6,545,761	4/8/2003	Aziz et al.			
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	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

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MD	AL	WO 2004/023071	3/18/2004	WIPO	G01B	11/06		
	AM							
	AN							
	AO							
	AP							

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	AS	
	AT	

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